Supporting Information for

# **Directional Electromagnetic Interference Shielding Based on**

## **Step-Wise Asymmetric Conductive Networks**

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## **Supplementary Figures and Table**

Fig. S1 Schematic diagram for the syntheses of Ni@MF



Fig. S2 SEM images of (a) pure MF and (b) Ni@MF-5



Fig. S3 SEM image of Ni@MF-5 at high magnification



**Fig. S4 SEM images of Ni@MF with different plating time.** SEM images of (**a** and **b**) Ni@MF-1, (**c** and **d**) Ni@MF-2, and (**e** and **f**) Ni@MF-3

Nano-Micro Letters



Fig. S5 Ni percentage in Ni@MF as a function of plating time



Fig. S6 SEM images of Ni@MF/CNT-75/PBAT composites with different Niplating time. SEM images of (a-c) MF/CNT-75/PBAT composites, (d-f) Ni@MF-1/CNT-75/PBAT composites, (g-i) Ni@MF-2/CNT-75/PBAT composites, and (j-l) Ni@MF-3/CNT-75/PBAT composites



**Fig. S7 SEM images of Ni@MF-3/CNT/PBAT composites with different CNT thickness.** SEM images of (**a-c**) Ni@MF-3/PBAT composites, (**d-f**) Ni@MF-3/CNT-25/PBAT composites, (**g-i**) Ni@MF-3/CNT-50/PBAT composites, (**j-l**) Ni@MF-3/CNT-75/PBAT composites, and (m-o) Ni@MF-3/CNT-100/PBAT composites



Fig. S8 The thickness of CNT/PBAT layer in Ni@MF-3/CNT/PBAT composites with different CNT paper thickness



Fig. S9 The magnified XRD pattern of PBAT in 10-30°



**Fig. S10** Resistance and conductivity of (**a**) Ni@MF with different plating time and (**b**) CNT papers with various thickness



Fig. S11 Bottom surface resistance and conductivity of Ni@MF/CNT/PBAT composites



Fig. S12 The average (a)  $SE_R$  and (b) R coefficients of Ni@MF/CNT-75/PBAT composites at different incident directions



Fig. S13  $\Delta$ SE<sub>R</sub> and SE<sub>R</sub> enhancement of Ni@MF/CNT-75/PBAT composites at different incident directions



Fig. S14 EMI SE<sub>A</sub> in X-band for Ni@MF/CNT-75/PBAT composites, when the EM wave is incident form (a) Ni@MF layer and (b) CNT layer



**Fig. S15** A coefficients in X-band for Ni@MF/CNT-75/PBAT composites, when the EM wave is incident form (**a**) Ni@MF layer and (**b**) CNT layer



Fig. S16  $\Delta$ SE<sub>A</sub> and SE<sub>A</sub> enhancement of Ni@MF/CNT-75/PBAT composites at different incident directions



Fig. S17 (a) EMI SE<sub>T</sub>, (b) SE<sub>A</sub>, and (c) SE<sub>R</sub> in X-band for Ni@MF-3/CNT/PBAT composites, when the EM wave is incident from Ni@MF layer



**Fig. S18** (a) A coefficients and (b) R coefficients in X-band for Ni@MF-3/CNT/PBAT composites, when the EM wave is incident from Ni@MF layer



Fig. S19 (a) The average SE<sub>T</sub>, SE<sub>A</sub>, and SE<sub>R</sub>, and (b) average A-R coefficient of Ni@MF-3/CNT/PBAT composites with the incident EM wave from Ni@MF layer



**Fig. S20** The Young's modulus of pure PBAT and step-wise asymmetric Ni@MF/CNT-75/PBAT composites with different Ni plating time



**Fig. S21** The fracture strain of pure PBAT and step-wise asymmetric Ni@MF/CNT-75/PBAT composites with different Ni plating time

Sample	Elemental content (at%)			
	C 1s	O 1s	N 1s	Ni 2p
Pure MF	66.3	14.6	19.1	-
Ni@MF-5	53.3	13.3	17.4	15.6

Table S1 Atomic percentages of pure MF and Ni@MF-5

Movie S1 Practical application for directional EMI shielding